## Amendments to the Specification:

Please replace paragraph [003] with the following amended paragraph:

[003] The mini-environment, generally indicated at 15, serves as a clean environment for wafer scheduling and handling. Such a mini-environment may be a SMIF-300 Wafer Management System available from Asyst Technologies, Inc. of Fremont, CA. It includes an enclosure 16 and several (two in this example) wafer pod loaders 21 and 22 for wafer pods 23 and 24 (Fig. 2), respectively. Each wafer pod 23, 24 contains a stack of wafers to be processed by the station 10. The enclosure 16 houses one or more robots (two in this example) 25 and 27 for transferring the wafers 28 from the pods to the load lock chamber 13. A suitable track robot is available from Equipe Technologies of Sunnyvale, CA. The robot 19 27,29 is also used to transfer wafers to and from the wafer aligner 18.

Please replace paragraph [0025] with the following amended paragraph:

[0025] The bottom wall 352 362 of the bottom plate member 234 has three receptacles 356a-356c (also depicted in phantom in Fig. 3a) secured to the bottom wall 352 362 of the carrier. In the illustrated embodiment, each receptacle 356a-356c is formed as a removable separate piece (Fig. 4) of steel or other suitable material, which is received in a generally rectangular opening 358 formed through the bottom wall 352 362 of the bottom plate member 234. Suitable fasteners such as rivets, bolts or screws may be passed through openings of a flange 360 on each side of the receptacle to secure the receptacle to the underside of the bottom plate member. The fasteners are preferably removable fasteners. Alternatively, the receptacles may be integrally formed with the carrier tool.

Please replace paragraph [0030] with the following amended paragraph:

[0030] The alignment of the carrier tool-port to the factory interface FOUP door opener mechanism may be tested by commanding the door opener mechanism to insert the

engagement members or heads 520 of the door opener registration pins into the two alignment registration holes 510a and 510d emulating the two alignment registration holes of a door of a FOUP type carrier. If the carrier support platform of the carrier tool-port is properly aligned with respect to the factory interface FOUP door opener mechanism, the head 520 of the registration pin will be received into the corresponding door alignment registration pin hole as illustrated in Fig. 6a for the alignment hole 510a of the insert 218a. On the other hand, if the door opening mechanism and the tool-port are misaligned, the head 520 of the opener mechanism will engage the front surface 506 of the alignment insert 218a and begin to push the insert 218a out of the insert opening 222a in the door plate member 226. This movement of the insert provides a clear indication to the operator of the misalignment condition.

Please replace paragraph [0039] with the following amended paragraph:

[0039] Figs. 8 and 9a, 9b show the insert 218b having, like the inserts 218a and 218d, a generally cylindrical outer surface 800 of an insert body 802 which is received by the generally cylindrical shaped opening 222b of the door plate member 226. The body 802 of the insert 218a 218b is inserted into the opening 222a 222b from the back side 803 of the door plate member 226 until a flange 804 at the rear of the insert 218b engages the back surface 803 of the door plate member 226. The front surface 806 of the insert 218a 218b defines a generally rectangular-shaped opening 810a 810b which is shaped and dimensioned in accordance with the SEMI standard E62-0299 for one of the two FOUP latch key holes. In this standard, the ends of the opening 810a 810b are rounded with a defined radius of curvature centered in the opening. The flange 804 of the insert 218b defines an opening 808 which receives a registration pin 809 disposed on the back surface 803 of the door plate member 226. When the insert 218b is inserted into the opening 222b of the door plate member 226, and the registration pin 809 is inserted into the flange opening 808 as shown in Fig 9a, the insert key opening 810b is positioned in accordance with the SEMI standard E62-0299 for one of the two FOUP door alignment key holes. The insert 218c is constructed in a similar manner such that the insert opening 810c of the insert 218c is positioned in accordance with the SEMI standard E62-0299 for the other of the two FOUP door key holes. In this manner, the insert openings 810b and 810c emulate the two SEMI E62-0299 FOUP door key for two latch keys of the factory interface

door opening mechanism.

Please replace paragraph [0040] with the following amended paragraph:

[0040] In a manner similar to that of the door opener registration pins of the robot, the alignment of the carrier tool-port to the factory interface FOUP door opener mechanism may be tested by commanding the door opener mechanism of the robot to insert the engagement members or heads 820 of the door opener latch keys into the two key holes 810b and 810c emulating the two key holes of a door of a FOUP type carrier. If the carrier tool-port is properly aligned with respect to the factory interface FOUP door opener mechanism, the head 820 of the carrier door latch key 821 will be received into the corresponding door key hole as illustrated in Fig. 9a for the key hole 810b of the key hole insert 218b. On the other hand, if the door opening mechanism and the tool-port are misaligned, the head 820 of the key 821 of the opener mechanism will engage the front surface 806 of the key hole insert 218b and begin to push the insert 218b out of the opening 222b in the door plate member 226. This movement of the insert provides a clear indication to the operator of the key to key hole misalignment condition.